FPD Materials & Components and FPD Metrology

Japan Joint TC Chapter

Meeting Summary and Minutes

Japan Standards Summer 2021 Meetings
Friday, July 9, 2021, 14:30-17:00(JST)
WEB

TC Chapter Announcements

Next TC Chapter Meeting

< FPD Materials & Components >

Friday, November 5, 2021, 14:30-16:30[JST]

Web / SEMI Japan office, Tokyo, Japan.

<FPD Metrology>

Date and Time to be decided

Table 1 Meeting Attendees

Italics indicate virtual participants

<Joint FPD Materials & Components > Co-Chairs: Tadahiro Furukawa (Yamagata University) / Yoshi Shibahara (FUJIFILM)
<Joint FPD Metrology > Co-Chairs: Ryoichi Watanabe (Japan Display) / Akira Kawaguchi (Otsuka Electronics)
SEMI Staff: Mami Nakajo (SEMI Japan)

Company	*Last*	*First*	*Company*	*Last*	*First*
FUJIFILM	*Ishizuka*	*Hiroshi*	*Sumitomo Bakelite*	*Eguchi*	*Toshimasa*
FUJIFILM	*Shibahara*	*Yoshi*	*Teijin*	*Ito*	*Haruhiko*
HOYA	*Ihara*	*Hirofumi*	*Yamagata University*	*Furukawa*	*Tadahiro*
Japan Display	*Watanabe*	*Ryoichi*	*SKE-Electronics CO., LTD.*	*Miyazaki*	*Shohei*
MORESCO	*Uehigashi*	*Atsushi*	*NIPPON STEEL Chemical &Material*	*Nakatsuka*	*Jun*
SK-Electronics CO., LTD.	*Miyazaki*	*Shohei*	*Sony Corporation*	*Tomioka*	*Satoshi*
Otsuka Electronics Co., Ltd.	*Kawaguchi*	*Akira*	SEMI Japan	Nakajo	Mami

Table 2 Leadership Changes

WG/TF/SC/TC Name	*Previous Leader*	*New Leader*
< FPD Materials & Components >		
None		
< FPD Metrology >		
None		

Table 3 Committee Structure Changes

Previous WG/TF/SC Name	*New WG/TF/SC Name or Status Change*
< FPD Materials & Components >	
None	
< FPD Metrology >	
None	

Table 4 Ballot Results

Document #	*Document Title*	*Committee Action*
< FPD Materials & Components >		
6694	**Line Item Revision to SEMI D74-0116: Guide for Measuring Dimensions for Plastic Films/Substrates**	
Line Item 1	Change 'shall' to 'should' as shown in section 6	**Passed with Editorial Change**
Line Item 2	Change sentences that use 'recommend(ed)' to sentences that use 'should' in section 6	**Passed as balloted**
Line Item 3	Addition of measuring machine name in 6.1.1	**Passed as balloted**
< FPD Metrology >		
None		

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS between meetings of the TC Chapter

#	*Type*	*SC/TF/WG*	*Details*
< FPD Materials & Components >			
None			
< FPD Metrology >			
None			

Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

#	*Type*	*SC/TF/WG*	*Details*
< FPD Materials & Components >			
None			
< FPD Metrology >			
None			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:
http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF

Table 7 Authorized Ballots

#	*When*	*TF*	*Details*
< FPD Materials & Components >			
6745	Cycle 6-2021	Maintenance Task Force	SNARF for: Line Item Revision to SEMI D50-0316: "TEST METHOD FOR SURFACE HARDNESS OF FLAT PANEL DISPLAY (FPD) COMPONENTS"
< FPD Metrology >			
None			

Table 8 SNARF(s) Granted a One-Year Extension

#	*TF*	*Title*	*Expiration Date*
< FPD Materials & Components >			
None			
< FPD Metrology >			
None			

Table 9 SNARF(s) Abolished

#	*TF*	*Title*
< FPD Materials & Components >		
None		
< FPD Metrology >		
None		

Table 10 Standard(s) to receive Inactive Status

Standard Designation	*Title*
< FPD Materials & Components >	
None	
< FPD Metrology >	
None	

Table 11 New Action Items

Item #	*Assigned to*	*Details*
< FPD Materials & Components >		
20210709-01	Mami Nakajo (SEMI Staff)	To forward the following ballot that passed at this TC Chapter meeting to the next A&R. o #6694: Line Item Revision to SEMI D74-0116: Guide for Measuring Dimensions for Plastic Films/Substrates

Table 11 New Action Items

Item #	*Assigned to*	*Details*
20210709-02	Hiroshi Ishizuka (FUJIFILM Corporation)	to prepare the ballot submission for Cycle 6-2021. o #6745: Line Item Revision to SEMI D50-0316: “TEST METHOD FOR SURFACE HARDNESS OF FLAT PANEL DISPLAY (FPD) COMPONENTS
< FPD Metrology >		
None		

Table 12 Previous Meeting Action Items

Item #	*Assigned to*	*Details*
< FPD Materials & Components >		
20201127-01:	Atsushi Uehigashi (MORESCO)	To prepare for a response to a comment from Steve Martell (Nordson SONOSCAN) on Ballot #6547 and send it to him via SEMI Japan staff **>Closed**
20201127-02:	Hiroshi Ishizuka (FUJIFILM)	To review SEMI D50-0316: Test Method for Surface Hardness of FPD Polarizing Film for 5-Year-Review and decide future action on the document. **>Closed**
20201127-03:	Chie Yanagisawa (SEMI Japan)	To forward all the ballots that passed at this TC Chapter meeting to the next A&R. **> Closed**
20210319-01	Mami Nakajo (SEMI Staff)	To send the minutes of the previous FPD M&C Committee meeting to the cochairs and upload it properly on the website.**>Open**
20210319-02	Mami Nakajo (SEMI Staff)	To confirm the status of the following documents that passed at the previous TC Chapter meeting on November 26,2020. • #6633: Revision to SEMI D42-0308 (Reapproved 0815): Specification for Ultra Large Size Mask Substrate Case • #6634: Revision to SEMI D53-0708 (Reapproved 0815): Specification for Liquid Crystal Display (LCD) Pellicles **>Closed**
20210319-03	Haruhiko Itoh (Teijin) Tadahiro Furukawa (Yamagata University)	to prepare the ballot submission for Cycle 4-2021. • #6694: Line Item Revision to SEMI D74-0116 “Guide for Measuring Dimensions of Plastic Films/Substrates” **>Closed**
20210319-04	Hiroshi Ishizuka (FUJIFILM Corporation)	to prepare a revised manuscript for SEMI D50 by the next TC Chapter meeting. • #6745: SNARF for: Line Item Revision to SEMI D50-0316: “TEST METHOD FOR SURFACE HARDNESS OF FLAT PANEL DISPLAY (FPD) COMPONENTS” **>Closed**
< FPD Metrology >		
20180528-01	SEMI Japan staff	To ask SEMI Korea staff who actually attended the FPD metrology Korea TC Chapter meeting held on April 13, 2018, because there are only two attendees recorded on the list of the FPD Metrology Korea TC Chapter meeting minutes held on April 13, 2018 and none of them are the chairs. In addition to that, no SEMI staff name is recorded in the minutes. **>Closed**
20190531-01	SEMI Japan staff	To send the discussion described in 7.3.1 of this meeting by the Japan TC Chapter of FPD Materials & Components GTC and the Japan TC Chapter of FPD Metrology GTC to SEMI Taiwan staff. **>Closed**

1 Welcome, Reminders, and Introductions

Tadahiro Furukawa (Yamagata University) called the meeting to order at 14:30. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01-02_Required Element Nov 2020 Rev1_E+J_r1,

2 Review of Previous Meeting Minutes

FPD Materials & Components Japan TC Chapter reviewed the previous Japan TC Chapter meeting minutes held on March 19, 2021.

Motion:	Approve the previous meeting minutes as written with editorial changes
By / 2nd:	Yoshi Shibahara (FUJIFILM) / Hirofumi Ihara (HOYA)
Discussion:	None
Vote:	11 in favor and 0 opposed. Motion Passed with changed.

Attachment: 02-01_20210319_FPD-M&C_Japan_MeetingMinutes_final_R1

FPD Metrology Japan TC Chapter reviewed the previous Japan TC Chapter meeting minutes held on May 31, 2019.

Motion:	Approve the previous meeting minutes as written
By / 2nd:	Akira Kawaguchi (Otsuka Electronics) / Tadahiro Furukawa (Yamagata University)
Discussion:	None
Vote:	10 in favor and 0 opposed. Motion Passed

Attachment: 02-02_20190531_FPD-M&C=FPD-Met_MeetingMinutes_M&C-approved

3 Liaison Reports

3.1 *FPD Metrology Korea TC Chapter*

Mami Nakajo (SEMI Japan) reported for the FPD Metrology Korea TC Chapter as attached material.

Attachment: 03-01_Liaison report_FPDM_KR_July2021

3.2 *FPD Metrology Taiwan TC Chapter*

Mami Nakajo (SEMI Japan) reported for the FPD Metrology Taiwan TC Chapter as attached material.

Attachment: 03-02_FPD-M Taiwan Liaison report_20210205_V1

3.3 *SEMI Staff Report*

Mami Nakajo (SEMI Japan) gave the SEMI Staff Report.

Attachment: 04-01_Staff Report July 2021_v1_Update_20210709

4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

4.1 < *FPD Materials & Components* >

Cycle 4-2021 submitted by the Japan TC Chapter

4.1.1 Document # 6694: Line Item Revision to SEMI D74-0116: Guide for Measuring Dimensions for Plastic Films/Substrates

4.1.1.1 Line Item 1: Change 'shall' to 'should' as shown in section 6

4.1.1.2 Line Item 2: Change sentences that use 'recommend(ed)' to sentences that use 'should' in section 6

4.1.1.3 Line Item 3: Addition of measuring machine name in 6.1.1

Action Item 20210709-01: Mami Nakajo (SEMI Staff) :To forward the ballot that passed at this TC Chapter meeting to the next A&R.

Attachment: 6694_Ballot Report template(LI)_r1,

4.2 < *FPD Metrology* >

None

5 Subcommittee and Task Force Reports

5.1 < *FPD Materials & Components* >

5.1.1 <*Flexible Display Task Force*>

Tadahiro Furukawa (Yamagata University) and Haruhiko Itoh (Teijin Limited) reported for the task force as attached.

- #6694: Line Item Revision to SEMI D74-0116 "Guide for Measuring Dimensions of Plastic Films/Substrates"
    - Passed as balloted at Ballot Review section of this meeting

Attachment: 05-01_FlexibleTF(20210709),

5.1.2 <*FPD Mask Task Force*>

Hirofumi Ihara (HOYA) reported for the task force as attached.

Attachment: 05-02_210706 Minutes FPD_Mask_TF,

5.1.3 <*FPD Materials & Components Maintenance Task Force*>

Hiroshi Ishizuka (FUJIFILM Corporation) reported for the task force as attached.

Attachment: 05-03_20210709 Maintenance TF report

< *FPD Metrology* >

5.1.4 < *FPD Metrology* Japan Chapter>

Ryoichi Watanabe (Japan Display) reported for the FPD Metrology as attached.

Attachment: 20210709 FPD Met avtivity report r3,

6 Old Business

6.1 < *FPD Materials & Components* >

6.1.1 < Project Period Review >

There is no need to take an action for extension.

6.1.2 5 Year Review Check

All targeted documents are addressed at the related task forces.

The review of the following two documents is assigned to Hiroshi Ishizuka (FUJIFILM Corporation).

- SEMI D39-0704 (Reapproved 0117) - Specification for Markers on FPD Polarizing Films
- SEMI D 34-0710 (Reapproved 0117)- Test Method for FPD Polarizing Films

6.2 < *FPD Metrology* >

None

7 New Business

7.1 < *FPD Materials & Components* >

7.1.1 New Ballots Authorization

7.1.1.1 #6745*:* Line Item Revision to SEMI D50-0316: "TEST METHOD FOR SURFACE HARDNESS OF FLAT PANEL DISPLAY (FPD) COMPONENTS"

Hiroshi Ishizuka (FUJIFILM Corporation) explained the details of the revised part and then proposed as following item.

Motion:	Authorize the Ballot (Line Item Revision to SEMI D50-0316: "TEST METHOD FOR SURFACE HARDNESS OF FLAT PANEL DISPLAY (FPD) COMPONENTS") Submission for Cycle 6-2021
By / 2nd:	Hiroshi Ishizuka (FUJIFILM Corporation)/ Hirofumi Ihara (HOYA)
Discussion:	None
Vote:	11 in favor and 0 opposed. Motion passed.

Action Item 20210709-02: Hiroshi Ishizuka (FUJIFILM Corporation) to prepare the ballot submission for Cycle 6-2021.

7.2 < *FPD Metrology* >

None

8 Action Item Review

8.1 < *FPD Materials & Components* >

8.1.1 Open Action Items

The following action item is open from the previous meeting.

20201127-01:	Atsushi Uehigashi (MORESCO)	To prepare for a response to a comment from Steve Martell (Nordson SONOSCAN) on Ballot #6547 and send it to him via SEMI Japan staff **>Closed**
20201127-02:	Hiroshi Ishizuka (FUJIFILM)	To review SEMI D50-0316: Test Method for Surface Hardness of FPD Polarizing Film for 5-Year-Review and decide future action on the document.

		>Closed
20201127-03:	Chie Yanagisawa (SEMI Japan)	To forward all the ballots that passed at this TC Chapter meeting to the next A&R. **> Closed**
20210319-01	Mami Nakajo (SEMI Staff)	To send the minutes of the previous FPD M&C Committee meeting to the cochairs and upload it properly on the website.**>Open**
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20210319-03	Haruhiko Itoh (Teijin) Tadahiro Furukawa (Yamagata University)	to prepare the ballot submission for Cycle 4-2021. • #6694: Line Item Revision to SEMI D74-0116 “Guide for Measuring Dimensions of Plastic Films/Substrates” **>Closed**
20210319-04	Hiroshi Ishizuka (FUJIFILM Corporation)	to prepare a revised manuscript for SEMI D50 by the next TC Chapter meeting. • #6745: SNARF for: Line Item Revision to SEMI D50-0316: “TEST METHOD FOR SURFACE HARDNESS OF FLAT PANEL DISPLAY (FPD) COMPONENTS” **>Closed**

8.1.2 New Action Items

The TC Chapter reviewed the following items.

20210709-01	Mami Nakajo (SEMI Staff)	To forward the following ballot that passed at this TC Chapter meeting to the next A&R. o #6694: Line Item Revision to SEMI D74-0116: Guide for Measuring Dimensions for Plastic Films/Substrates
20210709-02	Hiroshi Ishizuka (FUJIFILM Corporation)	to prepare the ballot submission for Cycle 6-2021. o #6745: Line Item Revision to SEMI D50-0316: “TEST METHOD FOR SURFACE HARDNESS OF FLAT PANEL DISPLAY (FPD) COMPONENTS

8.2 < *FPD Metrology* >

8.2.1 Open Action Items

The following action item is open from the previous meeting.

20180528-01	SEMI Japan staff	To ask SEMI Korea staff who actually attended the FPD metrology Korea TC Chapter meeting held on April 13, 2018, because there are only two attendees recorded on the list of the FPD Metrology Korea TC Chapter meeting minutes held on April 13, 2018 and none of them are the chairs. In addition to that, no SEMI staff name is recorded in the minutes. **>Closed**

20190531-01	SEMI Japan staff	To send the discussion described in 7.3.1 of this meeting by the Japan TC Chapter of FPD Materials & Components GTC and the Japan TC Chapter of FPD Metrology GTC to SEMI Taiwan staff. **>Closed**

8.2.2 New Action Items

None

9 Next Meeting and Adjournment

The next meeting is not jointly held. The meetings are scheduled as follows. See http://www.semi.org/standards-events for the current list of events.

The next FPD Materials & Components Japan TC Chapter meeting is scheduled as follows.

Date: Friday, November 5, 2021

Time: 14:30-16:30

Place: Web / SEMI Japan office, Tokyo, Japan.

The next FPD Metrology Japan TC Chapter meeting is scheduled as follows.

Date and Time to be decided

Adjournment: [17:00]>.

Respectfully submitted by:

Mami Nakajo

Coordinator

SEMI Japan

Phone: +81.3.3222.5949

Email: mnakajo@semi.org

Minutes tentatively approved by:

Tadahiro Furukawa (Yamagata University), Co-chair	07 19,2021
Yoshi Shibahara (FUJIFILM), Co-chair	07 16,2021
Ryoichi Watanabe (Japan Display) Co-chair	07 16,2021
Akira Kawaguchi (Otsuka Electronics) Co-chair	07 19,2021

Table 13 Index of Available Attachments[#1]

Title	*Title*
01-02_Required Element Nov 2020 Rev1_E+J_r1	04-01_Staff Report July 2021_v1_Update_20210709
02-01_20210319_FPD-M&C_Japan_MeetingMinutes_final_R1	05-01_Flexible TF(20210709)
02-02_20190531_FPD-M&C=FPD-Met_MeetingMinutes_M&C-approved	05-02_210706 Minutes FPD_Mask_TF

Table 13 Index of Available Attachments[#1]

03-01_Liaison report_FPDM_KR_July2021	05-03_20210709 Maintenance TF report
03-02_FPD-M Taiwan Laision report_20210205_V1	05-04_20210709 FPD Met avtivity report r3

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.